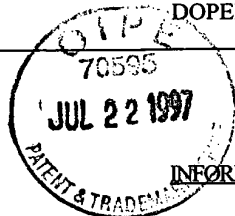


Applicant: Kei-Yu Ko
Serial No.: 08/846,671 Att'y Docket No. 11675.114
Filing Date: April 30, 1997
For: UNDOPED SILICON DIOXIDE AS AN ETCH STOP FOR SELECTIVE ETCH OF
DOPED SILICON DIOXIDE

INFORMATION DISCLOSURE CITATIONS MADE BY APPLICANTU.S. Patent Documents

Examiner Initial*	Patent Number	Issue Date	Name	Class	Sub Class	Filing Date
<u>GA</u> A1	5,286,344	2/15/94	Blalock et al.	156	657	6/15/92
A2	5,366,590	11/22/94	Kadomura	156	662	3/17/94
<u>GA</u> A3	5,423,945	6/13/95	Marks et al.	156	662.1	9/8/92
A4						
A5						

Foreign Patent Documents

Examiner Initial*	Document Number	Publ. Date	Country or Patent Office	Sub Class	Class	Trans- lation
A6						
A7						

Other Documents

(including author (if listed), title, relevant pages, date of publication including at least month and year).

Examiner
Initial*

A8

Examiner: George Goudreau Date Considered: 2-2,000

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

(Use several sheets if necessary)

Group Art Unit ~~1764~~ 1765

SHEET 1 OF 1